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**INNOWACYJNA
GOSPODARKA**
NARODOWA STRATEGIA SPÓJNOŚCI

UNIA EUROPEJSKA
EUROPEJSKI FUNDUSZ
ROZWOJU REGIONALNEGO



DKZ/26/2009

Warsaw, 19.05.2009.

Re: The open procedure for delivery of the system for dielectrics films deposition by sputtering technique

With regard to the following questions:

Does this mean that delivered system will need to have built in process for AR and HR coating production for a particular diode lasers or is it enough for the system to produce suitable quality films and AR, HR coating design and structure will be decided and designed by customer?

we inform that:

The Awarding Entity will design suitable quality films and AR, HR coatings for different semiconductor lasers. The Awarding Entity will make sputtering processes as with use of a special holder which height is up to 1cm (the holder will be provided by the customer), as on the substrates of different shapes and sizes from 5mmx5mm up to circles with diameter of 2''.

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